



Mirror absorption bench setup and commissioning

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Face2Face Meeting, Toyama University August 28th, 2015

Introduction

Motivation:

• Minimize mirror optical absorption to make cryogenic operation as easy as possible.

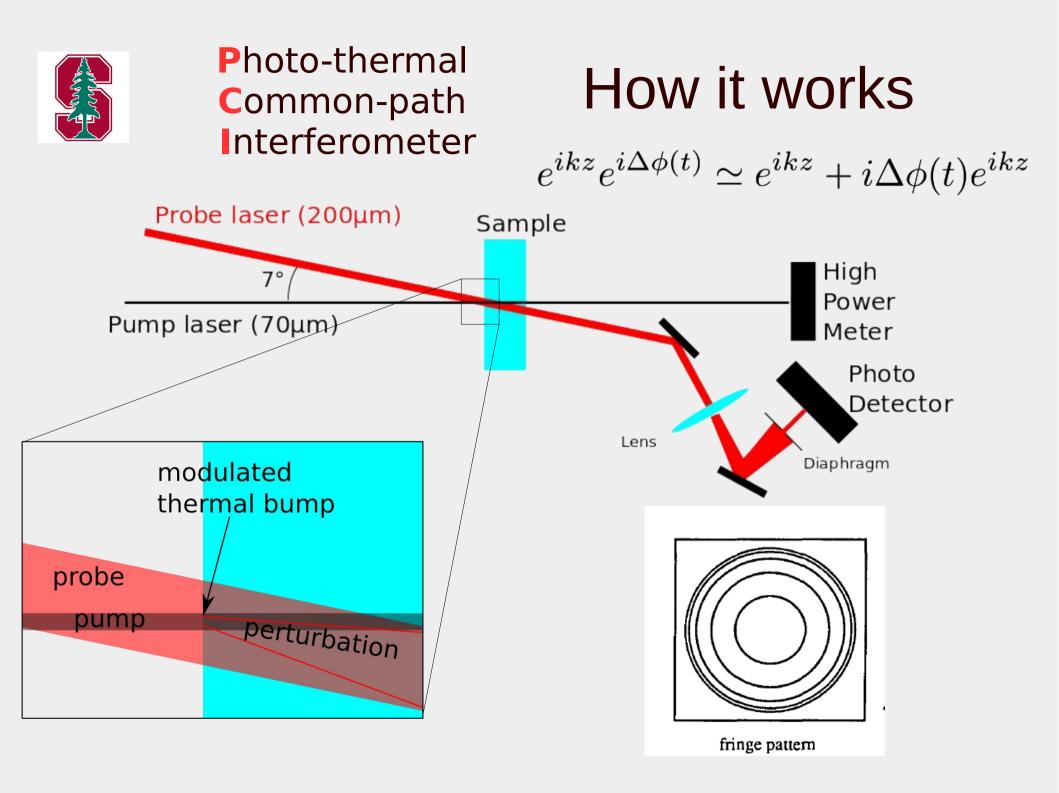
Objectives:

- Measure absorption of KAGRA
 substrates and coatings
- Investigate new mirror materials for future upgrades

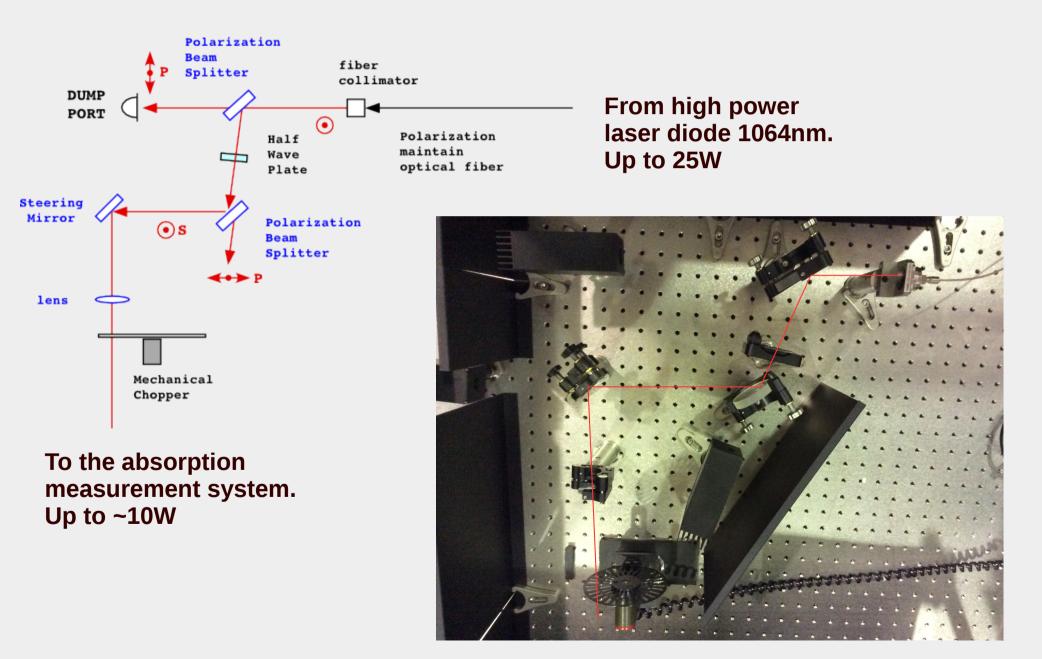
Steps:

- Setup optical absorption measurement system
- Validate the calibrations
- Make absorption measurements

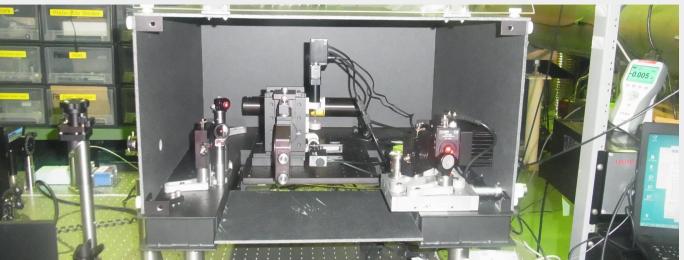


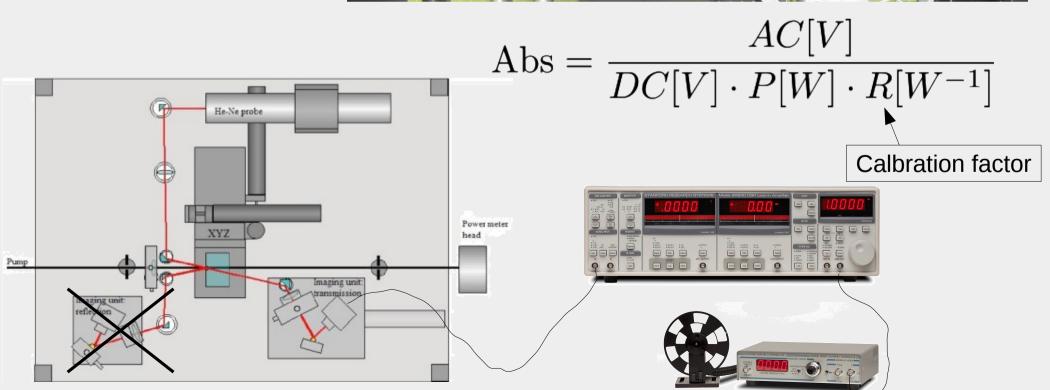


Experimental setup: pump beam



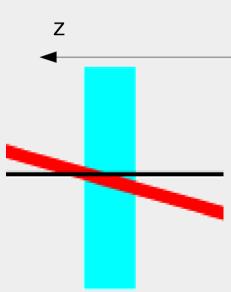
Experimental setup: absorption measurement system





Scanning along Z axis

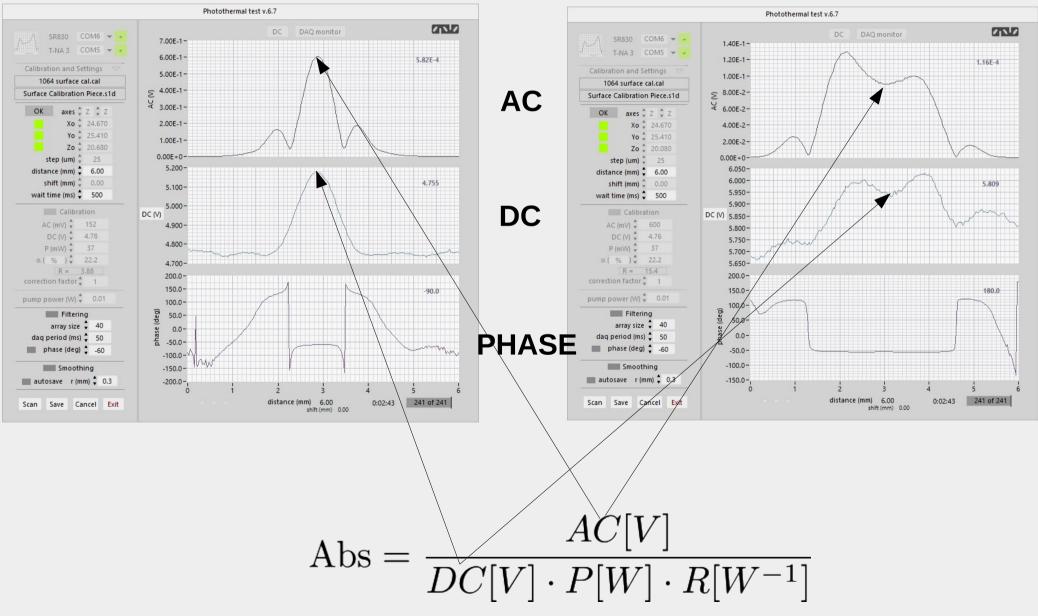




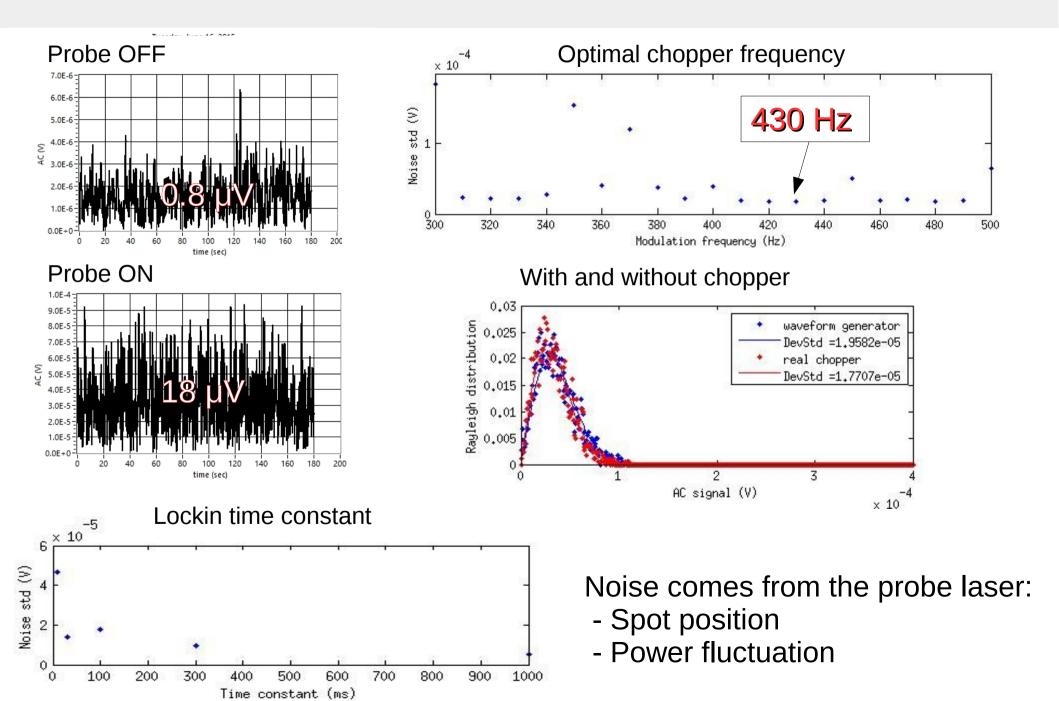
Measurements:

SURFACE ABSORPTION

BULK ABSORPTION



Noise level



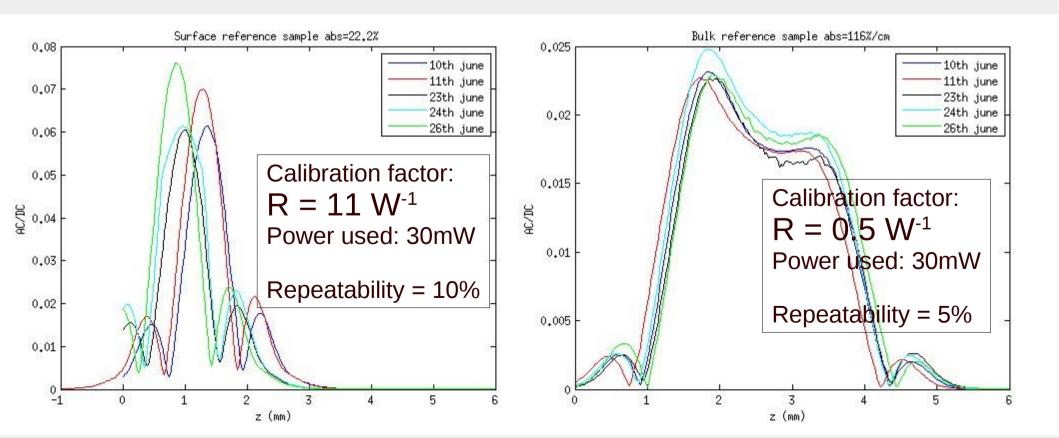
Calibrations

SURFACE Reference sample:

Newport FRQ-ND02 Nominal absorption: **22.2%** at 1064 nm Spectrophotometer measurement: **22.0%** Thickness 3mm

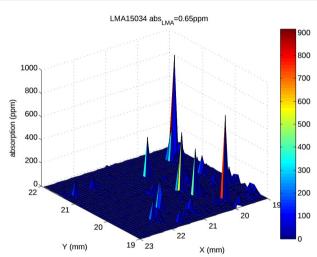
BULK Reference sample:

Schott glass NG-12 Nominal absorption: **116%/cm** at 1064 nm Spectrophotometer measurement: **104%/cm** Thickness 3.6mm



LMA Surface sample: Maps Maps

Surface sample 15034 nominal = 0.65ppmpump power = 6.3WResolution 70µm x 70µm measured = 0.85ppm



LMA15034 abs_{LMA}=0.65ppm

X (mm)

0.95

0.9

0.85

0.8

0.75

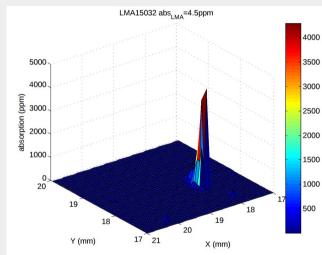
0.7

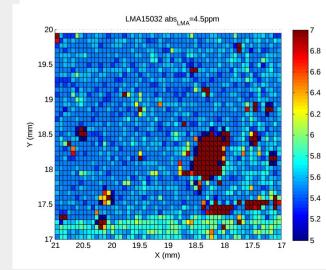
0.65

0.6

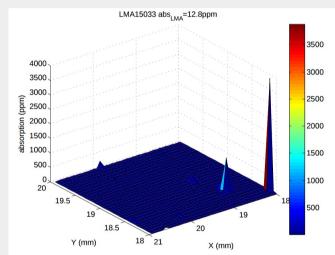
0.55

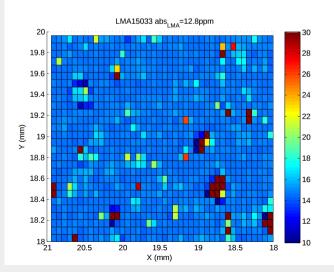
Surface sample 15032 nominal = **4.5ppm** pump power = 3.36W Resolution = 70µm x 70µm measured = **5.4ppm**





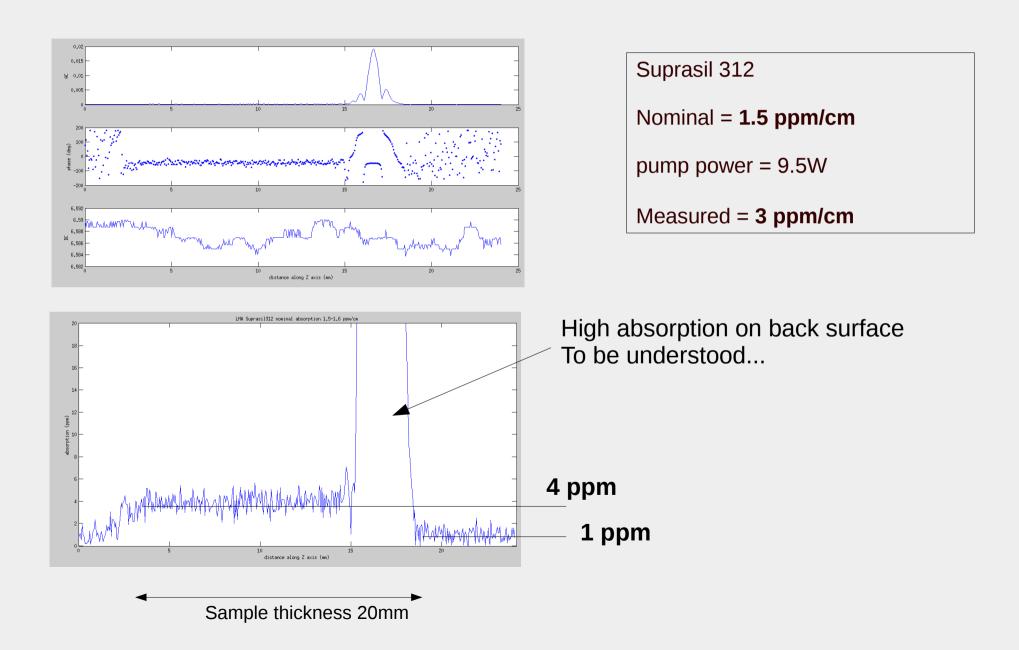
Surface sample 15033 nominal = **12.8ppm** pump power = 1.18W Resolution = 70µm x 70µm measured = **14ppm**



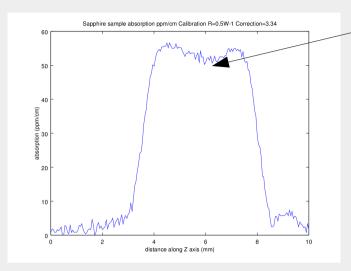




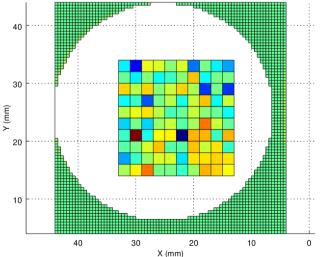
LMA Bulk sample

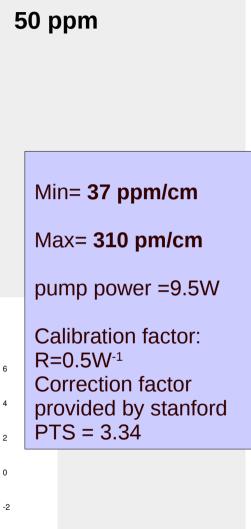


Sapphire sample from Shinkousha



Sapphire bulk absorption ppm/cm (difference between 2 measurements)



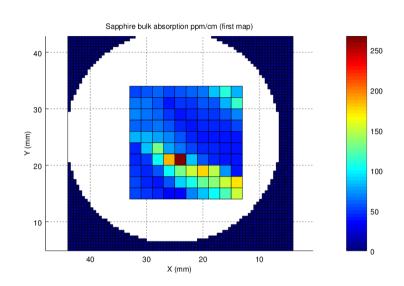


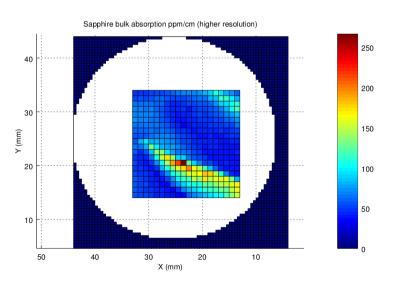
4

2

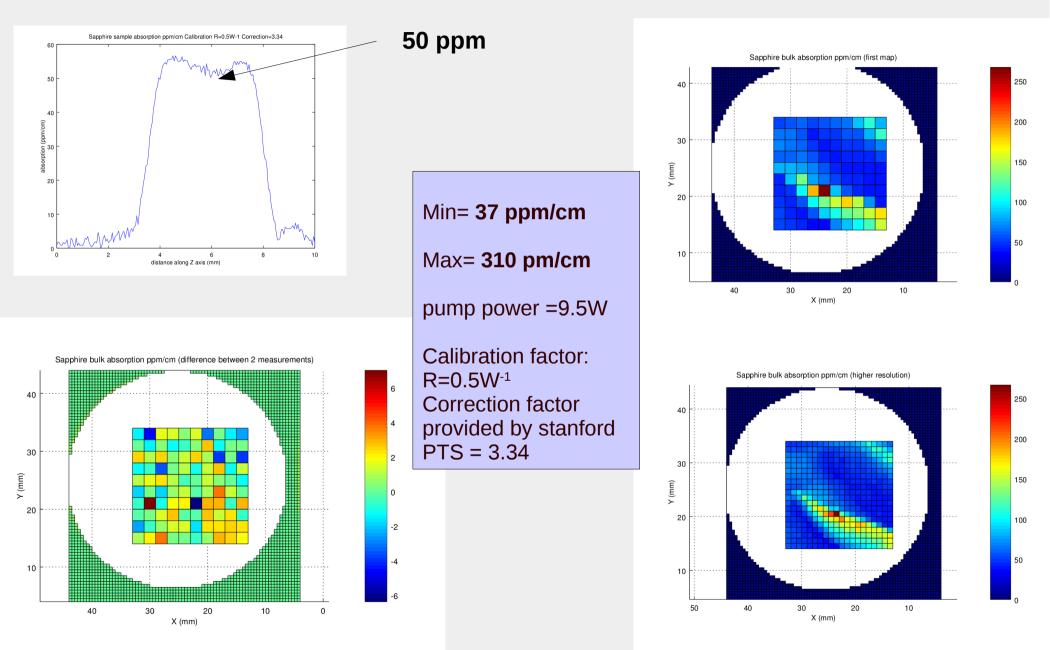
0

-4





Sapphire sample from Shinkousha

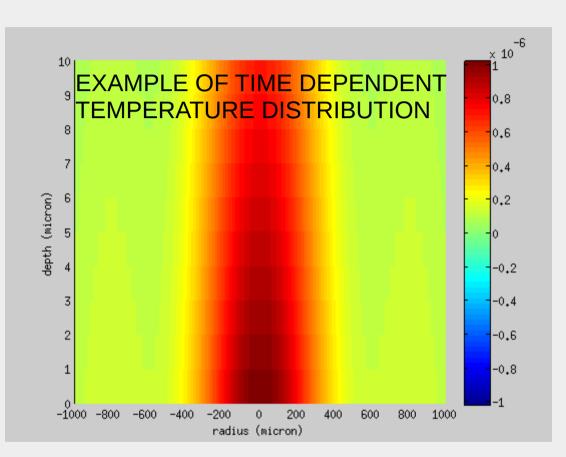


NOT HOMOGENEOUS

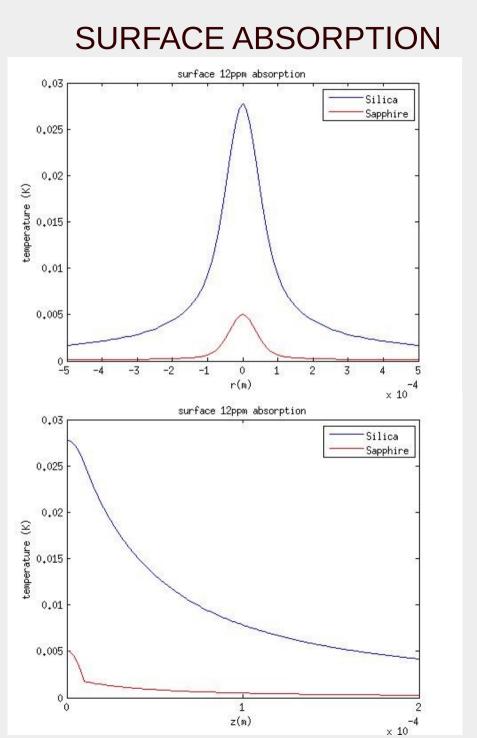
Next steps: correction factor for different materials

- Calculate temperature distribution for different thermal parameter
- Use refraction index distribution in an optical simulator (OSCAR)
- Calculate the expected signals for several thermal parameters
- Calculate how the calibration factor changes





Temperature distribution for Silica and Sapphire



BULK ABSORPTION 10 × 10 Bulk 20ppm/cm absorption Silica Sapphire 8 6 temperature (K) 4 2 -0.04 -0.03 -0.02 -0.01 -0.05 0.01 0.02 0 0.03 0.04 0.05 r(m)-3 x 10 Bulk 20ppm/cm absorption 1 0.9 0.8 Silica Sapphire 0.7 € 0.6 temperature 0.5 0.4 0.3 0.2 0.1

2.5

z(m)

2

3.5

4

3

4.5

x 10

5

-3

Û

Û

0.5

1

1.5

Summary and Perspectives

STATUS

Absorption bench operating

•NEXT STEPS

- •Set the translation stage for large mirrors
- •Installing everything in the clean room
- •Measure KAGRA substrates (scan and maps)
- Measure KAGRA coatings
- Investigate new materials for future mirrors

Aknowledgment to:

 Danièle Forest, Laurent Pinard and Gerome Degallaix of Laboratoire des Matériaux Avancés (LMA), Lyon, France for providing the samples and a lot of useful advices

Thank you for the attention!